

Notice of References Cited	Application/Control No. 09/804,158	Applicant(s)/Patent Under Reexamination KAWADA ET AL.	
	Examiner Kripa Sagar	Art Unit 1756	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,635,315	06-1997	Mitsui, Masaru	430/5
	B	US-5,863,393	01-1999	Hu, Yongjun	204/192.3
	C	US-6,139,698	10-2000	Wang et al.	204/192.15
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Motegi et al. : "Long throw low pressure sputtering technology for very large scale integrated devices"; JI.Vac.Sc.Tech. B, v13(1995),pp1906-1909
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.